

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.  
26860/33:47 USSERIAL NO.  
08/651,036INFORMATION DISCLOSURE CITATION  
(Use several sheets if necessary)APPLICANT  
Mark D. Owen, Bonnie A. Larson, Jozef Van,  
PuymbroeckFILING DATE  
May 17, 1996GROUP  
2106

## PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
cm	AA	4 9 7 0 3 6 9	11/13/90	Yamazaki et al.	219	121.85	
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	AL							
	AM							
	AN							
	AO							
	AP							

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

AR		
AS		
AT		

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MAR 11 1997

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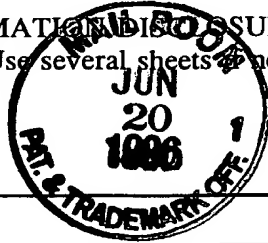
EXAMINER

Gregory Hill

DATE CONSIDERED

4-4-97

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FORM PTO-1449  
(REV. 7-80)U.S. DEPARTMENT OF COMMERCE  
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EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
Am	AA	5 3 7 8 8 6 9	01/03/95	Marrs et al.	219	121.71	
Am	AB	5 2 9 3 0 2 5	03/08/94	Wang	219	121.71	
Am	AC	5 1 9 4 7 1 3	03/16/93	Egitto et al.	219	121.71	
Am	AD	5 1 6 8 4 5 4	12/01/92	LaPlante et al.	219	121.8	
Am	AE	5 1 5 3 4 0 8	10/06/92	Handford et al.	219	121.64	
Am	AF	5 1 0 8 7 8 5	04/28/92	Lincoln et al.	427	96	
Am	AG	5 0 8 7 3 9 6	02/11/92	Zablotny et al.	<del>264</del>	<del>25</del>	
Am	AH	5 0 7 3 6 8 7	12/17/91	Inagawa et al.	219	121.7	AUG 22 1996
Am	AI	5 0 6 3 2 8 0	11/05/91	Inagawa et al.	219	121.7	GROUP 210
Am	AJ	4 9 1 5 9 8 1	04/10/90	Traskos et al.	<del>427</del>	<del>53.1</del>	
Am	AK	4 8 9 4 1 1 5	01/16/90	Eichelberger et al.	219	121.69	
Am	AL	4 8 3 2 7 8 8	05/23/89	Nemiroff	<del>156</del>	<del>643</del>	
Am	AM	3 9 3 1 4 5 8	01/06/76	Dini	358	297	
Am	AN	3 6 3 2 3 9 8	01/04/72	Konig	<del>117</del>	<del>93.3</del>	

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
Am	AO	0 5 8 0 4 0 8	01/26/94	EPC	B23K	26/00		
Am	AP	0 2 3 5 1	02/01/96	PCT	B23K	26/00		
Am	AQ	1 2 8 3 0	05/02/96	PCT	C23C	14/04		

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

Am	AR	"LaserPulse," Electro Scientific Industries, Inc., Fall 1993, pp. 1-7 Am 4-4-97						
Am	AS	Richard Harris et al., "MGM Micromachining: Nd:YAG UV Laser Process is a New Option," Electro Scientific Industries, Inc., Spring 1993						

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## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

cm	AT	"Etch-Stop Polymer Machining with an Argon Ion laser," IBM TECHNICAL DISCLOSURE BULLETIN, Jan 1993, Vol. 36., No. 1, Armonk, NY, US, p. 254
cm	AU	"Dopant-Induced Excimer Laser Ablation of Poly(tetrafluoroethylene)," APPLIED PHYSICS B:PHOTO- PHYSICS AND LASER CHEMISTRY, Mar 92, Vol b54, No. 3, C.R. David et al., pp. 227-230
cm	AV	Friedrich G. Bachmann, "Large scale industrial application for excimer-lasers; via-hole-drilling by photo-ablation," SPIE, V. 1361, Physical Concepts of Materials for Novel Optoelectronic Device Applications, 1990, pp 500-511

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AUG 22 1996

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